ECE 485  **MEMS Devices & Systems**  credit: 3 hours.
Introduction to principles, fabrication techniques, and applications of microelectromechanical systems (MEMS). In-depth analysis of sensors, actuator principles, and integrated microfabrication techniques for MEMS. Comprehensive investigation of state-of-the-art MEMS devices and systems. Same as ME 485.

<table>
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<th>CRN</th>
<th>Type</th>
<th>Section</th>
<th>Time</th>
<th>Days</th>
<th>Location</th>
<th>Instructor</th>
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<td>36987</td>
<td>Lecture</td>
<td>C</td>
<td>09:30 AM - 10:50 AM</td>
<td>TR</td>
<td>245 - Everitt Laboratory</td>
<td>Liu, G</td>
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Credit Hours: 3 hours